

**Chemical Mechanical Polishing In Silicon Processing,  
Volume 63 (Semiconductors & Semimetals) (Vol 63)**

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BACKGROUND OF THE INVENTION. 1. Field of the Invention. The invention pertains to a chemical mechanical abrasive composition. The chemical mechanical abrasive <http://www.google.com/patents/US6303049>

Books and Book Chapters; Modeling and Simulation, in Chemical Mechanical Polishing in Silicon Processing, Semiconductors and Semimetals, vol. 63, <https://www-mtl.mit.edu/wpmu/researchgroupsboning/publications/books-and-book-chapters/>

Photodetectors, Silicon: Photosensors or photodetectors are sensors of light or other electromagnetic energy. Chemical detectors, such as photographic plates, [http://www.electronicdesignnet.com/cms/component/option.com\\_ebg/Itemid,92/task.cos/eid,21318.16388.17974/](http://www.electronicdesignnet.com/cms/component/option.com_ebg/Itemid,92/task.cos/eid,21318.16388.17974/)

(e.g. chemical mechanical polishing) 49, 50, 51, 52) used mostly in optical and semiconductor manufacturing Annual Review of Materials Science Vol. 19 <http://www.annualreviews.org/doi/full/10.1146/annurev.matsci.30.1.27>

Shin et al., Chemical Mechanical Polishing in Silicon Processing 2000; Vol. 63. 228 from a semiconductor wafer after chemical-mechanical <http://www.google.tl/patents/US6875087>

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in Chemical Mechanical Polishing in Silicon Process-ing, Semiconductors and Semimetals, Vol. 63, Eds. S. H. Li Faculty, Research Staff, and Publications [http://www-mtl.mit.edu/research/annual\\_reports/2000/Staffpubs.pdf](http://www-mtl.mit.edu/research/annual_reports/2000/Staffpubs.pdf)

Chemical mechanical polishing is currently used to manufacture the silicon wafers as the final material removal process to meet (MRR) in polishing of silicon wafers. <http://krex.k-state.edu/dspace/handle/2097/475>

A model for wafer scale variation of material removal rate in chemical mechanical polishing Chemical Mechanical Polishing in Silicon Processing, vol. 63 . 6  
<http://link.springer.com/article/10.1007%2Fs11664-002-0044-4>

Chemical Mechanical Planarization from Macro-Scale to IEEE Transactions on Semiconductor Manufacturing model for chemical-mechanical polishing of silicon  
<http://www.tandfonline.com/doi/full/10.1080/10426914.2011.593244>

Semiconductors and Semimetals Volume 92, Pages 2-181 Chemical Mechanical Polishing in Silicon Processing Wafering of Silicon; Pages 63-109;  
<http://www.sciencedirect.com/science/bookseries/00808784>

The Semiconductor Manufacturing. Chemical-mechanical polishing: Silicon Processing for the VLSI Era: Volume 1-Process Technology  
<http://www.erc.arizona.edu/Education/MME%20Course%20Materials/MME%20Modules/Reference/Reference%20list.doc>

High density plasma etching of single crystalline 'Pattern geometry effects in the chemical-mechanical polishing of semiconductors and semimetals' Vol. 63  
[http://www.koreascience.or.kr/article/ArticleFullRecord.jsp?cn=GJSJBE\\_2005\\_v15n6\\_234](http://www.koreascience.or.kr/article/ArticleFullRecord.jsp?cn=GJSJBE_2005_v15n6_234)

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<http://www.barnesandnoble.com/w/chemical-mechanical-polishing-volume-566-s-v-babu/1110954224?ean=9781558994737>

Particle Scale Modeling of Material Removal and Surface Roughness in Chemical Mechanical Polishing. Like most semiconductor manufacturing silicon polishing  
<http://ufdc.ufl.edu/UFE0012201/00001>

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[http://www.koreascience.or.kr/article/ArticleFullRecord.jsp?cn=GJSJBE\\_2005\\_v15n1\\_34](http://www.koreascience.or.kr/article/ArticleFullRecord.jsp?cn=GJSJBE_2005_v15n1_34)

Silicon Processing for the VSLI ERA." Chemical Mechanical Polishing for Dielectric Layers. now This invention relates to semiconductor manufacture. and  
<http://patentimages.storage.googleapis.com/pdfs/US5795495.pdf>

This and other objectives are satisfied by the present invention in providing a slurry for chemical mechanical polishing chemical mechanical polishing silicon  
<http://www.google.com/patents/US6627107>

What is Chemical Mechanical Polishing or CMP Polishing? Chemical Mechanical Polishing is more commonly known as CMP Polishing. Silicon Wafer CMP;  
<http://www.logitech.uk.com/applications/cmp.aspx>

Chemical mechanical polishing in silicon processing. Semiconductors conditioning in chemical mechanical polishing: Manufacturing Technology Volume  
<http://link.springer.com/article/10.1007%2Fs00170-012-4480-x>